



**Editorial** 

## Acknowledgment to the Reviewers of Nanomanufacturing in 2022

Nanomanufacturing Editorial Office

MDPI AG, St. Alban-Anlage 66, 4052 Basel, Switzerland

High-quality academic publishing is built on rigorous peer review. *Nanomanufacturing* was able to uphold its high standards for published papers due to the outstanding efforts of our reviewers. Thanks to the efforts of our reviewers in 2022, the median time to first decision was 17 days and the median time to publication was 49 days. Regardless of whether the articles they examined were ultimately published, the editors would like to express their appreciation and thank the following reviewers for the time and dedication that they have shown *Nanomanufacturing*:

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